

Plasma FIB(Xe) and TOF-SIMS application capability

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A compact Time-of-Flight Secondary Ion Mass Spectrometer (TOF-SIMS) combined with Scanning Electron microscope equipped with a Focused Ion Beam (FIB-SEM) permits a novel quality of correlated microscopy and spectroscopy when using a variety of analytical add-ons. The orthogonal extraction design of the spectrometer allows continuous bombardment with a Ga or Xe-FIB, making the acquisition faster compared to a quadrupole mass spectrometer and providing a broad mass range at once. Precise detection of trace and light elements; distinguishing different isotopes; depth profiling are some of the advantages of this analytical correlative approach.